

Nanotechnology (physics)			
Sl.no	Equipment Name	Make (Manufacturer)	Equipment Description
1	Cleanroom	M+W Group	Micro and nano device fabrication lab
2	Electron Beam Evaporation Sysytem	Hind High Vacuum (HHV) company Pvt. Ltd.	Thin film deposistion
3	Semiconductor Device analyser	Agilent Technologies	Electrical measurements
4	Mask Aligner	Suss Microtec	for patterning devices
5	Profilometer	Ambios Technology	Thinfilm thickness and roughness measurement
6	Sputtering	Advanced Process Technology Pvt. Ltd.	Thin film deposistion
7	E-Beam & Thermal evaporation System	Hind High Vacuum (HHV) company Pvt. Ltd.	Thin film deposistion
8	RTA(Rapid Thermal Anealing)	Anneal Sys	Annealing @ 250 deg/sec
9	Raman/SNOM	Witec focus Innovations	Micro raman and AFM measuremnts
10	Tubular Furnace	Ants	Annealing the samples upto 1000 degrees
11	Scriber	Suss Microtec, Germany	Scribing the wafers into pieces
12	Thermal Evaporation	Hind High Vacuum (HHV) company Pvt. Ltd.	Thin film deposistion
13	Sputtering	Advanced Process Technology Pvt. Ltd.	Thin film deposistion
14	Dip coater	Holmarc	Coating the liquid samples
15	Hot Air Oven	Hi-Tech Instruments	Heating the samples upto 400 degrees
16	Hydraulic Press	Labwan	Preparation of pellets
17	Optical Microscope	Olympus Corporation	Inspection of samples
18	PPMS (Locaated in CIL)	Quantum Design	PPMS
19	SQUID (Located in CIL)	Quantum Design	SQUID
20	FT-NMR (Located in SoC)	Bruker	FT-NMR
21	Transmission Electron Microscope	FEI	Nanoscale Imaging technique
22	EBL	CRESTEC	To prepare the masks of nm scale design
23	ICP-RIE	OXFORD INSTRUMENTS	Dry etching
24	Wire Bonder	WESTBOND	Make gold contacts for fabricated devices
25	UV-Vis Spectrophotometer	JASCO	Study of Absorption, Reflection and Transmission of Samples
26	TEM Sample Preparation	Gatan	TEM Sample preparation